

Title (en)

METHOD OF MANUFACTURING A POLISHING PAD

Title (de)

VERFAHREN ZUM HERSTELLEN VON EINEM POLIERKISSEN

Title (fr)

PROCEDE DE FABRICATION D'UN TAMPON DE POLISSAGE

Publication

**EP 1011919 B1 20041020 (EN)**

Application

**EP 98938386 A 19980805**

Priority

- US 9816289 W 19980805
- US 5490697 P 19970806

Abstract (en)

[origin: WO9907515A1] Polishing pads are provided having a polishing surface formed from a hydrophilic material. The polishing surface has a topography produced by a thermoforming process. The topography consists of large and small features that facilitate the flow of polishing fluid and facilitate smoothing and planarizing.

IPC 1-7

**B24B 1/00**; **B24B 7/19**; **B24B 7/30**

IPC 8 full level

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CPC (source: EP KR)

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